Interconnect Crosstalk Analysis in Sub-powered Integrated Circuits

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Outline

- Motivation & Goal
- Introduction in interconnects
- Interconnect modeling
- SPICE simulations
- Conclusions

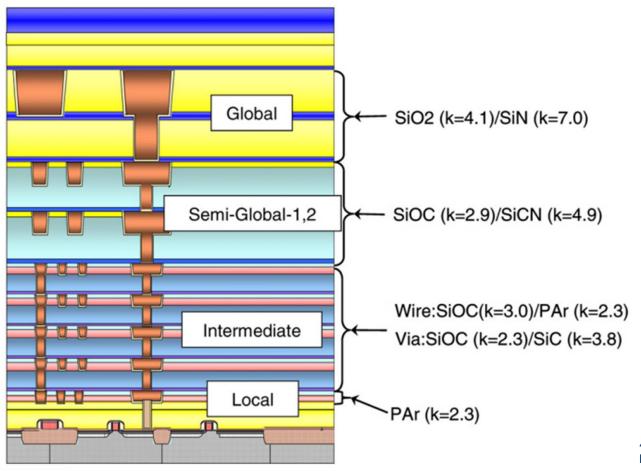
Motivation & Goals

- Determine data dependence error models for interconnects
 - Logic level alteration
 - Delay dependent error models
- Establish design guidelines for interconnects
 - Determine wire spacing & length
 - Parameters:
 - Supply voltage (range)
 - Dielectric material
 - Maximum number of accepted errors

Goals

- Determine the minimum spacing
 - Larger spacing -> greater cost
 - Increase number of wires on plane
 - Very large transports
- Determine the maximum length
 - Reduction of repeater buffers for long interconnects
 - Reduction of silicon usage
 - Reduction of metallic vias

Introduction in interconnect



45/32 nm CMOS – Challenge and perspective – K. Ishimaru, Solid State Electronics, 2008

$R = \frac{\rho \cdot l}{w \cdot t}$

Interconnect electrical properties

• Resistance

- Depends on physical characteristics
- Timing parameters of a wire

$$R = \rho * \frac{l}{S}$$

- Power consumption characteristics of a wire

Inductance

- Self inductance
 - Depends on the length & perimeter
 - Voltage increase/decrease when switching

$$L_{s} = \mu_{0} * \frac{l}{2\Pi} \left[\ln \left(\frac{2l}{p} \right) + \frac{1}{2} + 0.22 * \frac{p}{l} \right]$$

*ptm.asu.edu

Interconnect electrical properties

• Inductance

- Mutual inductance
 - Inductive cross-coupling
 - Wide range affect (spans multi-wires)
 - Depends on the wire spacing and length

$$M = \mu_0 * \frac{l}{2\Pi} \left[\ln \left(\frac{2l}{d} \right) - 1 + \frac{d}{l} \right]$$

Capacitance

- Ground capacitance
 - Depends on wire spacing & dielectric material

$$C_g = \varepsilon \left[\frac{w}{h} + 2.04 * \left(\frac{s}{s+0.54} * h \right)^{1.77} \right]$$

- Cross-coupled capacitance
 - Neighbor wires affected

$$C_{c} = \varepsilon \left[1.41 * \frac{t}{s} * e^{-\frac{4s}{s+8.01h}} + 2.37 * \left(\frac{w}{w+0.31s}\right)^{0.28} * \left(\frac{h}{h+8.91s}\right)^{0.76} * e^{-\frac{2s}{s+6h}} \right] * \text{ptm.asu.edu}$$

Noise sources in interconnects

- Crosstalk
 - Inductance/Capacitance crosstalk
 - Substrate crosstalk
 - Passive components in substrate
 - Power/ground line crosstalk
- Transmission line effects
 - Affects long lines (global)
 - Depends on the signal frequency
 - Due to impedance discontinuities
 - Vias, wire bends, cross-over lines, etc
 - Process defects (bubbles, diffusion, etc)
- Electro-magnetic interference

Interconnect modeling

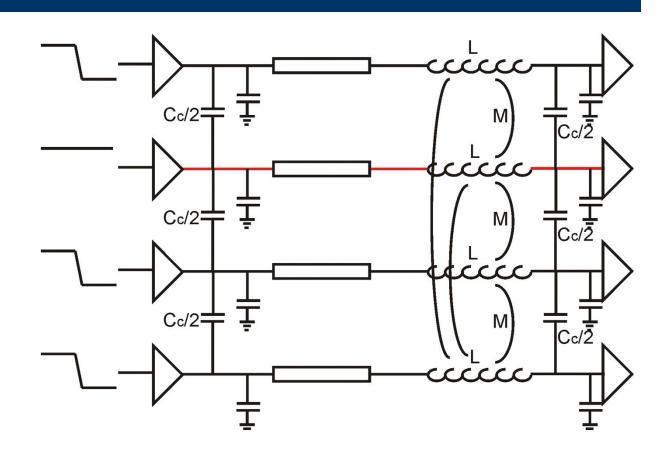
RC models

- Inductors' influence is around 5%
- Pi model of the wire
- RLC models
 - Include inductors
 - Second degree differential equations
- RLCG models
 - Include very large resistor between wires
 - Conductance through the dielectric material.

Simulation scenario

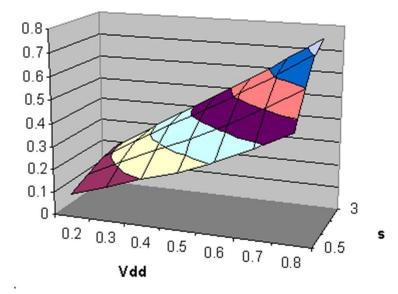
- 4-wire interconnect RLC model
- 4 driver buffers & 4 receiver buffers
- Victim line internal wire
- 560 simulations
- Parameters:
 - Spacing
 - Length
 - Dielectric constant
 - Vdd

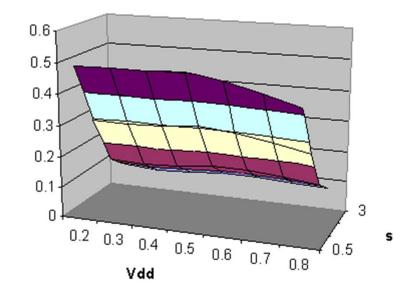
Simulation scenario



Simulation results Dependence on spacing

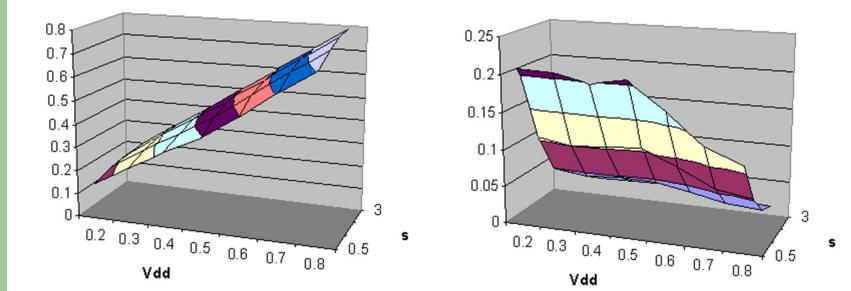






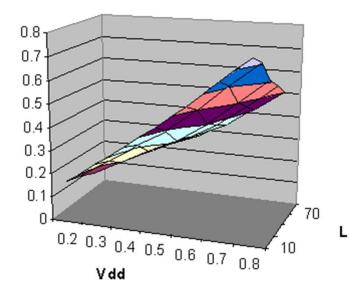
Simulation results Dependence on spacing

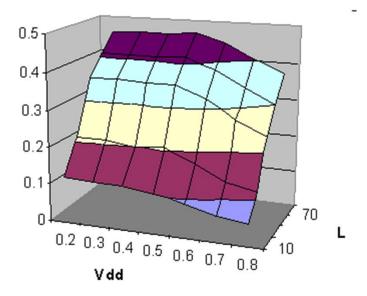




Simulation results Dependence on length

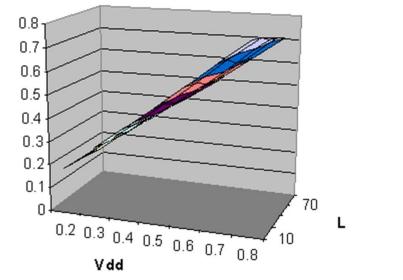
• k = 2.2 s = 0.5

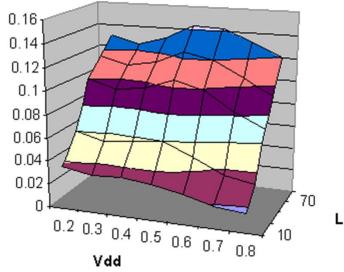




Simulation results Dependence on length

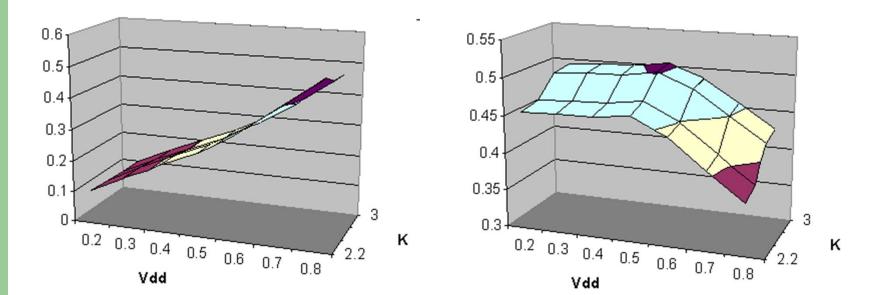
• k = 3 s = 2





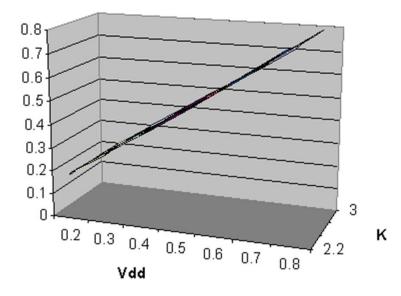
Simulation results Dependence on dielectric constant

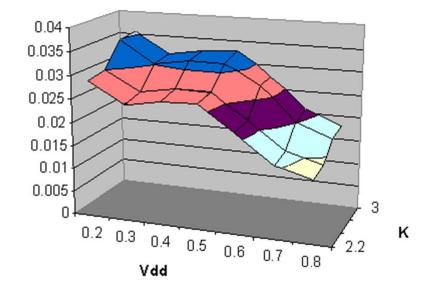




Simulation results Dependence on dielectric constant







Conclusions

- Investigate the crosstalk effects in low supply voltage regions of operations
- Investigate the influence of different parameters (length, spacing, dielectric material)
- Logic level drop small differences with respect to supply voltage
 - Maximum at around 0.5 V

Thank you